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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kiyoshi Arita  
Serial No.: 10/716,965 Art Unit: 2813  
Filed: November 19, 2003  
Title: "METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA  
PROCESSING APPARATUS AND PLASMA PROCESSING METHOD"  
Examiner: Thanh T. Nguyen  
Docket No.: 36280

RESPONSE AND ELECTION

Mail Stop Amendments  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Va. 22313-1450

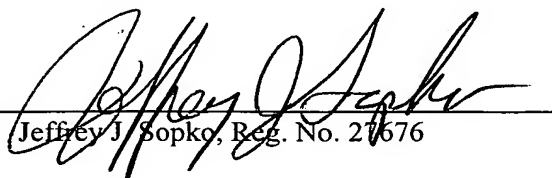
Sir:

This communication is filed in response to the Office action dated November 16, 2004. The one month period for responding to the Office action expires on December 16, 2004.

The Examiner has required Applicant to elect a single invention for prosecution on the merits. Applicant hereby elects to proceed with Invention I, claims 1-8 and 17-27 without traverse.

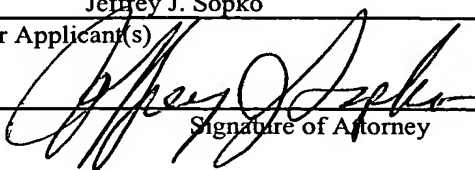
If there are any additional fees resulting from this communication, please charge same to our Deposit Account No. 16-0820, our Order No. 36280.

Respectfully submitted,  
PEARNE & GORDON LLP

By:   
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Date: November 30, 2004

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Mail Stop Amendments, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below.	
Jeffrey J. Sopko	
Name of Attorney for Applicant(s)	
11/30/2004	
Date	
	Signature of Attorney